

1-11. (Canceled).

12. (Currently Amended) A laser apparatus for material treatment, comprising:

a source of laser radiation providing pulsed laser radiation comprising a train of laser pulses; and

a deflecting device, which directs said laser radiation into the material at different, selectable locations to generate optical breakthroughs within the material; and

a pulse picking device that ~~changes~~ modifies selected laser pulses of the train of pulsed laser pulses radiation, with regard to at least one optical parameter of said ~~pulsed~~ selected laser pulses radiation, such that the ~~changed~~ selected laser pulses cannot generate optical breakthroughs; and, wherein

a control device that controls the operation of the pulse picking device such that the pulse picking device influences said selected laser pulses such that only a remaining subset of not selected laser pulses ~~[[can]]~~ cause optical breakthroughs ~~[[in]]~~ within the material.

13. (Currently Amended) The laser apparatus as claimed in claim 12, wherein the laser pulses of the train of laser pulses are substantially equidistant in time and wherein the control device is programmed to operate the pulse picking device such that the pulse picking device selects non-consecutive laser pulses of the train of ~~changes non-sequential~~ laser pulses, ~~which are~~ the selected laser pulses being substantially equidistant in time according to a selection frequency.

14. (Currently Amended) The laser apparatus as claimed in claim 12, wherein the control device is programmed to operate the pulse picking device such that the pulse picking device ~~changes~~ modifies the selected laser pulses at least with regard to one parameter selected from a group consisting of: phase, amplitude, polarization, propagation direction, and beam profile.

15. (Original) The laser apparatus as claimed in claim 12, wherein the pulse picking device comprises at least one structure selected from a group consisting of an acousto-optic modulator, a Pockels' cell, a fiber-optics switching element and a chopper wheel.

16. (Currently Amended) The laser apparatus as claimed in claim 12, ~~further comprising a~~ wherein the control device ~~[[which]]~~ synchronously controls the pulse picking device and the deflecting device.

17. (Original) The laser apparatus as claimed in Claim 13, wherein the control device controls the pulse picking device and the deflecting device to generate the optical breakthroughs along a predetermined path.

18. (Currently Amended) The laser apparatus as claimed in Claim 17, wherein the control device monitors an actual deflection speed of the deflecting device and if ~~[[an]]~~ the actual deflection speed of the deflecting device approaches a preselected maximum deflection speed,

the control device increases the selection frequency of pulses such that more pulses are selected and, ~~in accordance therewith,~~ also decreases the actual deflection speed.

19. (Currently Amended) A method of material treatment by laser radiation, comprising generating pulsed laser radiation comprising a train of laser pulses via a laser source controlled by a control unit;

variably deflecting the pulsed laser radiation into the material to generate optical breakthroughs within the material; and

~~changing~~ modifying selected laser pulses of the ~~pulsed train of laser pulses radiation~~, with regard to an optical parameter of said selected laser pulses ~~pulsed laser radiation~~, such that the ~~changed~~ selected laser pulses no longer generate optical breakthroughs, wherein only a remaining subset of not selected laser pulses ~~[[can]]~~ cause optical breakthroughs ~~[[in]]~~ within the material.

20. (Currently Amended) The method as claimed in Claim 19, wherein the laser pulses of the train of laser pulses are substantially equidistance in time and the method further comprising selecting non-consecutive non-sequential laser pulses of the train of laser pulses according to a selection frequency, which the selected laser pulses [[are]] being substantially equidistant in time, ~~to be changed according to a selection frequency.~~

21. (Currently Amended) The method as claimed in Claim 19, wherein the selected laser pulses are ~~changed~~ modified at least with regard to one parameter selected from a group consisting of: phase, amplitude, polarization, propagation direction, and beam profile.

22. (Original) The method as claimed in Claim 20, further comprising deflecting the laser radiation and the change in the selected laser pulses in a synchronized manner.

23. (Currently Amended) The method as claimed in Claim 19, further comprising controlling the deflection of the laser radiation and the ~~picking~~ selection of the laser pulses to cause optical breakthroughs to form along a predetermined path ~~[[in]]~~ within the material.

24. (Currently Amended) The method as claimed in Claim 23, further comprising, if an actual deflection speed of said deflection comes close to a maximum deflection speed, increasing the selection frequency of pulses such that more pulses are selected, and ~~in accordance therewith~~, simultaneously decreasing the actual deflection speed.

25. (New) The method as claimed in Claim 20, further comprising, if an actual deflection speed of said deflection comes close to a maximum deflection speed, increasing the selection frequency of pulses such that more pulses are selected, and simultaneously decreasing the actual deflection speed.